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Date: July 30, 2004

Jane Keating

Patent
36856.1187

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Takahiro OGUCHI	Art Unit: 2856
Serial No.: 10/725,874	Examiner: Unknown
Filed: December 2, 2003	
Title: METHOD OF MANUFACTURING AN EXTERNAL FORCE DETECTION SENSOR	

INFORMATION DISCLOSURE STATEMENT

U.S. PATENT AND TRADEMARK OFFICE
Mail Stop DD
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, submitted herewith are copies of eleven (11) references cited in the enclosed search report issued in a corresponding European patent application. For the Examiner's convenience, we have enclosed a copy of the European Examination Report and a completed Form PTO-1449. The statement is not a representation that all of the information cited is necessarily effective as prior art against the application.

08/05/2004 MMEKOWEN 00000011 501353 10725874

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I hereby state that each item of information contained in this Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than 3 months prior to the filing of this statement, and that this is the first citation of these prior art references by a foreign patent office in a counterpart foreign patent application. Accordingly, no fee is necessary for the filing of this statement. Should the Commissioner determine otherwise, the Commissioner is authorized to charge Deposit Account No. 50-1353 for any fee shortages, including the petition fee under 37 C.F.R. § 1.17(p).

Applicant(s) respectfully request(s) that the disclosed reference(s) be made of record in the subject application.

Respectfully submitted,

Date: July 30, 2004

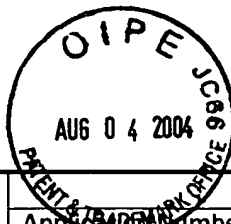


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PTO/SB/08A (04-03)

Substitute for form 1449/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Sheet 2 of 2

Complete if Known

Applicant Number	10/725,874
Filing Date	December 2, 2003
First Named Inventor	Takahiro OGUCHI
Art Unit	2856
Examiner Name	unknown
Attorney Docket Number	36856.1187

NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title Of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	8	ZHIXIONG et al., "LATERALLY CAPACITY SENSED ACCELEROMETER FABRICATED WITH THE ANODIC BONDING AND THE HIGH ASPECT RATIO ETCHING", Solid-State and Integrated Circuit Technology 1998 Proceedings, 5 th International Conference in Beijing, China, Oct. 21-23, 1998, pp. 921-924, IEEE, Piscataway, NJ.	
	9	MOCHIDA et al., "A MICROMACHINED VIBRATING RATE GYROSCOPE WITH INDEPENDENT BEAMS FOR THE DRIVE AND DETECTION MODES", Micro Electro Mechanical Systems 1999, MEMS '99, 12 th IEEE International Conference in Orlando, FL, Jan. 17-21, 1999, pp. 618-623, IEEE, Piscataway, NJ.	
	10	KLASSEN et al., "SILICON FUSION BONDING AND DEEP REACTIVE ION ETCHING: A NEW TECHNOLOGY FOR MICROSTRUCTURES", Proc. Of Transducers '95, 8 th International Conference on Solid-State Sensors and Actuators, Stockholm, Sweden, June 25-29, 1995, pp. 556-559, Vol. 1.	
	11	FRANSSILA et al., "ETCHING THROUGH SILICON WAFER IN INDUCTIVELY COUPLED PLASMA", Microsystem Technologies, , April 2000 (2000-04), pp. 141-144, vol. 6, no. 4, Berlin, DE.	

Examiner Signature		Date Considered	
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*Examiner: Initial if reference considered, whether of not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered, include copy of this form with next communication to applicant.

¹ Applicant unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached. This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14.